

**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Satoshi TATSUURA et al.

Group Art Unit: 1753

Application No.: 10/082,228

Examiner: E. Wong

Filed: February 26, 2002

Docket No.: 106200.01

For: METHOD FOR ELECTRODEPOSITED FILM  
FORMATION, METHOD FOR ELECTRODE  
FORMATION, AND APPARATUS FOR  
ELECTRODEPOSITED FILM FORMATION

**MAIL STOP RCE**

**LARGE ENTITY REQUEST FOR  
CONTINUED EXAMINATION UNDER 37 C.F.R. §1.114**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. §1.114, Applicants hereby request continued examination.

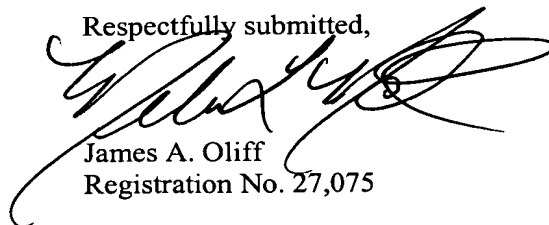
☒ Applicants further request entry and consideration of the submission filed October 13, 2004.

☒ Applicants further request entry and consideration of the attached submission.

The above-identified application was filed on or after June 8, 1995. Thus, entry is proper under 37 C.F.R. §1.114(d).

Attached hereto is our check no. 160954 in the amount of ☒ \$790.00 as payment of the fees set forth in 37 C.F.R. §1.17(e). The Commissioner is hereby authorized to charge any additional fees or credit any overpayment associated with this communication to Deposit Account No. 15-0461. Two duplicate copies of this page are enclosed.

Respectfully submitted,



James A. Oliff  
Registration No. 27,075

Melanie L. McCollum  
Registration No. 40,085

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JAO:MLM/jam

Date: November 26, 2004

**OLIFF & BERRIDGE, PLC**  
**P.O. Box 19928**  
**Alexandria, Virginia 22320**  
**Telephone: (703) 836-6400**

**DEPOSIT ACCOUNT USE  
AUTHORIZATION**

Please grant any extension  
necessary for entry;  
Charge any fee due to our  
Deposit Account No. 15-0461